MEMS Postdoctoral Researcher Position

Ultrasonic Micromotors Using Thin Film Piezoelectrics

A postdoctoral research position is available beginning in Aug/Sep 2009 for the development of a new class of ultrasonically-actuated silicon micromotor fabricated with integrated piezoelectric films. The position requires a strong background in silicon microfabrication process development. Experience with multi-wafer bonding and integration, piezoelectric MEMS fabrication and characterization, dynamic system and interfacial contact modeling, device testing, and/or related skill sets is highly desirable. Research will be performed at the University of Maryland and the nearby Army Research Laboratory. U.S. citizenship is required.

• Strong silicon microfabrication experience is required

• Must be a U.S. Citizen

• Position Opens August/September 2009

Email your CV and reference list to:

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